

**UCF MATERIALS CHARACTERIZATION FACILITY
ACADEMIC FEE SCHEDULE 2024-2025**

<u>Equipment</u>	<u>Hourly Rate</u>
Scanning Electron Microscopy (SEM)	
Zeiss Ultra-55	65
Transmission Electron Microscopy (TEM)	
Jeol JEM-1-11	40
Tecnai F30	85
Focused Ion Beam (FIB)	
FEI 200 TEM	60
Zeiss FIB Crossbeam	80
X-Ray Diffraction (XRD)	
XRD -- GN (Panalytical)	50
XRD -- EC (Panalytical)	65
XRD -- TF (Panalytical)	60
Secondary Ion Mass Spectrometry (SIMS)	
Cameca IMS-3F	60
PHI Adept	70
Miscellaneous	
XPS Escalab 250Xi	65
Sputter Coater (Quoram)	50
X-Ray Fluorescence Spectrometer (XRF) (Panalytical)	25
Other Instruments	
Critical Point Dryer	30
Diamond Wafering	30
Dimple Grinder	30
PECS Gatan (Coating System)	30
Ion Milling	30
Ultra Microtom (Leica)	30
Leica Trimmer	30
Metal Polisher Allied	30
Plasma Cleaner	30
Confocal Laser Scanning Microscope	30
Metallurgical Microscope	30
MicroRaman Spectroscopy	30
Profilometer	30
Reichert Optical Microscope	30